

EddyCus® map 2530MT – Metal Thickness Imaging Device

P 2530MT 22



Highlights

- ► High resolution (5 1,000,000 points)
- ► Contact-free (4PP replacement)
- ► Accurate with nanometer resolution
- ► High speed (0.5 to 30 minutes)
- ► Enables process wafer measurement
- ► Mapping of encapsulated layers
- ▶ Integrity and defect imaging

Processes

- Deposition (PVD, evaporation, plating, CVD, ALD etc.)
- Layer and material modification (implantation, doping, annealing)
- ► Layer removal (CMP, etching, scribing etc.)

Materials

- ► Semiconductor industry
- ▶ Electronic industry

Applications

- ► Metallization in photovoltaics
- ► Batteries, fuel cells, capacitors
- ▶ Boards and panels (PCB, WLP, PLP)
- ► Mirrors and lenses
- ▶ Barrier films
- ► EMC/EMI Shielding
- ► Heating and de-icing films
- Medical applications

- ► Metal films
- ► Metal meshes
- Metal substrates
- ► Alloy films
- ► Alloy substrates

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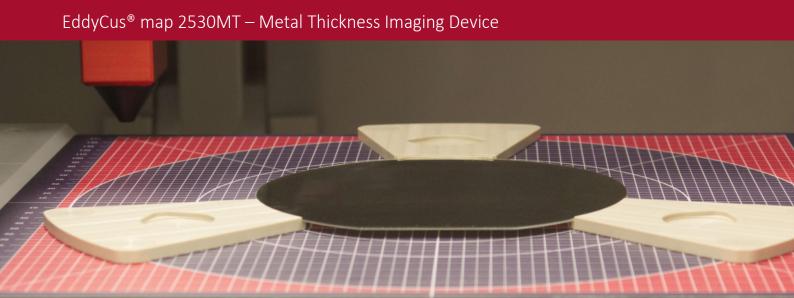
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Engineered and Made in Germany







Measurement technology	Non-contact eddy current sensor
Substrates	Wafer, glass, foil, etc.
Max. scanning area	12 inch / 300 mm x 300 mm (larger upon request)
Edge effect correction / exclusion	2 – 10 mm (depending on size, range, setup and requirements)
Max. sample thickness / sensor gap	3 / 5 / 10 / 25 mm (defined by the thickest sample)
Metal thickness range Accuracies depend on the selected setup and the type / conductivity of the metal (e.g. copper, aluminum, silver)	Low $1-10 \text{ nm}; 2-5 \%$ accuracy Standard $10-1,000 \text{ nm}; 1-3 \%$ accuracy High $1-100 \mu\text{m}; 0.5-3 \%$ accuracy
Metal thickness calibration	Direct thickness calibration / sheet resistance conversion
Sheet resistance range (optional)	0.1 mOhm/sq – 100,000 Ohm/sq (in 5 ranges)
Scanning pitch (X and Y)	1/2.5/5/10/25 mm
Scanning time	8 inch / 200 mm x 200 mm in 1.5 to 15 minutes (1 – 10 mm pitch) 12 inch / 300 mm x 300 mm in 2 to 15 minutes (2.5 – 25 mm pitch)
Device dimensions (w/h/d) / weight	31.5" x 19.1" x 33.5" / 799 mm x 486 mm x 850 mm / 90 kg
Further available features / other tool configurations	Sheet resistance measurement / conductivity / resistivity / anisotropy / permeability (beta)

Device Control and Software

- Pre-defined measurement and product recipes (sizes, pitches, thresholds)
- ▶ Line scan, histogram and area analysis
- ▶ Black and colored image coding
- ► Csv & pdf export
- ▶ SPC summary and export
- ▶ 3 user levels
- ► Material database for parameter conversion
- ► Edge effect compensation
- ► Storage and import of data
- ► Export of data sets (e.g. to EddyEva, MS Excel, Origin)

